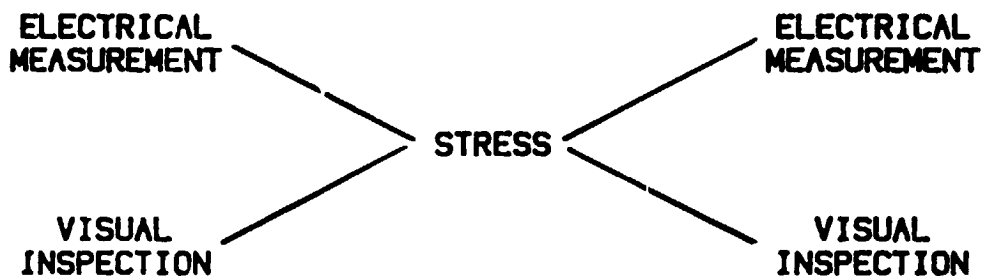


# AMORPHOUS-SILICON CELL RELIABILITY TESTING

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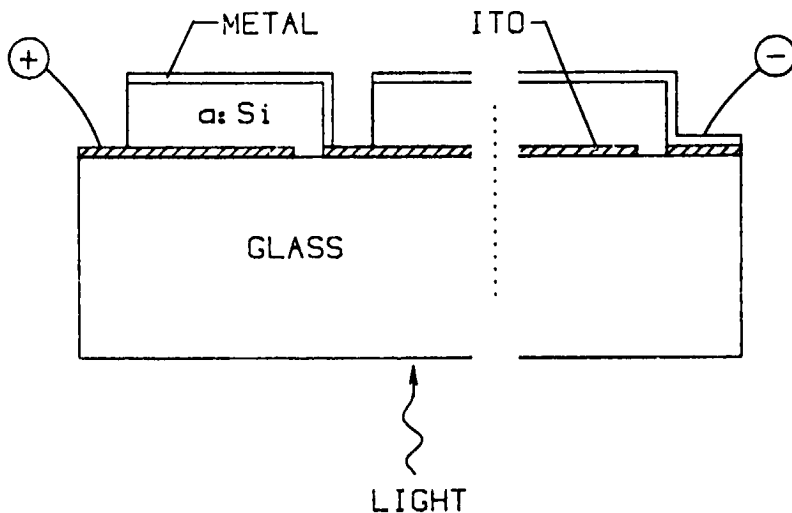
## Accelerated Stress Test Methodology



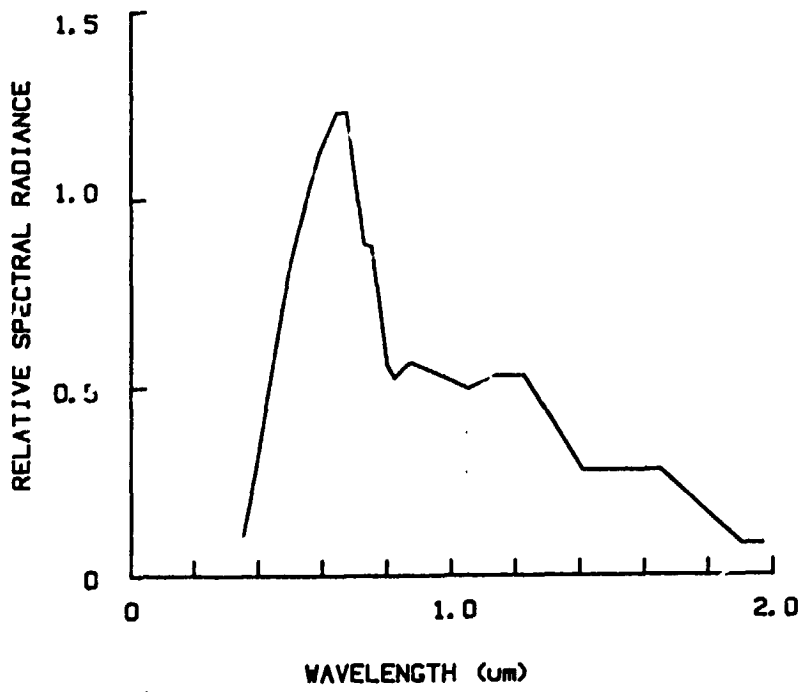
## Amorphous-Silicon Problem Areas

MEASUREMENT -- REFERENCE CELL  
INSPECTION -- SURFACE ANALYSIS METHODS  
STRESS -- TEST SCHEDULE

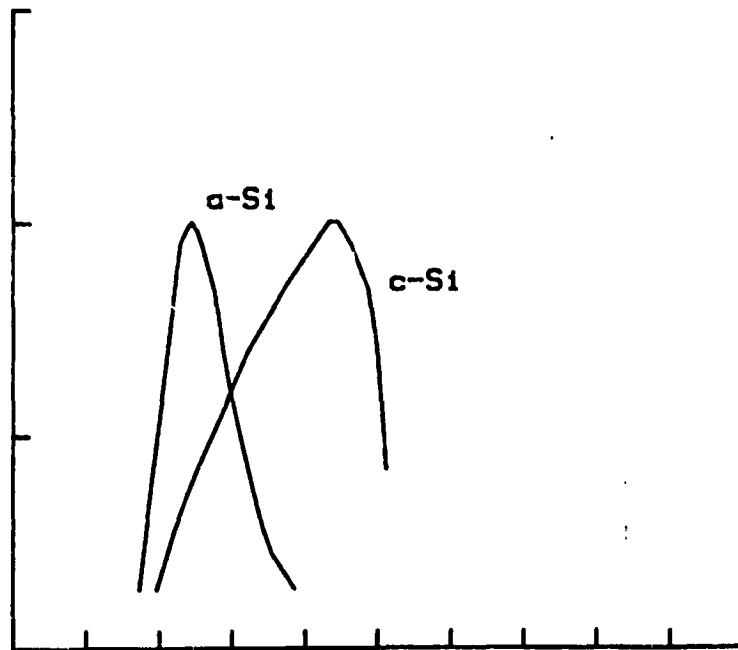
## Schematic Diagram of Amorphous-Silicon Monolithic Solar Panel



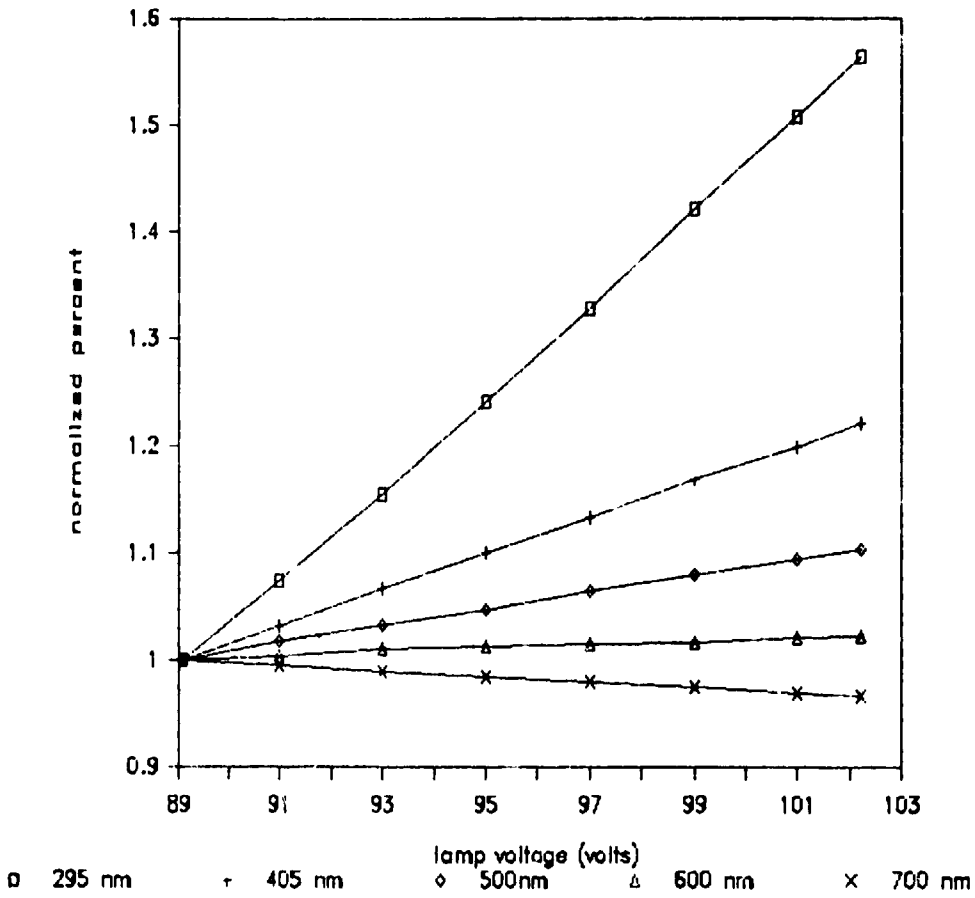
Relative Spectral Distribution of ELH Lamp



Relative Spectral Response



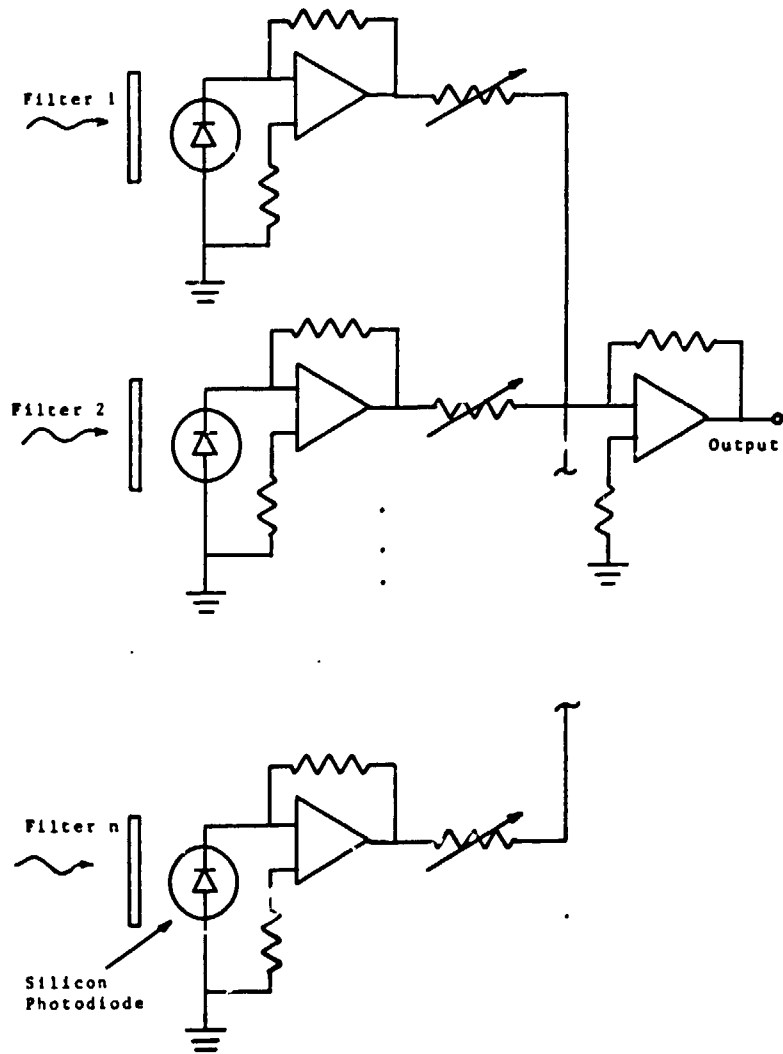
ELH Spectral Content Versus Lamp Voltage



Calibration and Measurement Procedures for Crystalline Cells

	RADIATION TYPE	SOURCE INTENSITY	SOURCE SPECTRAL DIST.	CELL	I (μt)
CALIBRATION	NATURAL	1-SUN	1-SUN	SMALL REFERENCE	$I_0$
	ELH	A	B	SMALL REFERENCE	$I_0$
	ELH	A	B	FULL STANDARD	$I_s$
MEASUREMENT	ELH	A'	B'	FULL STANDARD	$I_s$

Simulated Amorphous Reference Cell



MODULE DEVELOPMENT AND ENGINEERING SCIENCES

Calibration and Measurement Procedures for Crystalline Cells

	RADIATION TYPE	SOURCE INTENSITY	SOURCE SPECTRAL DIST.	CELL	I(out)
CALIBRATION	NATURAL	1-SUN	1-SUN	SMALL REFERENCE	$I_0$
	ELH	A	B	SMALL REFERENCE	$I_0$
	ELH	A	B	FULL STANDARD	$I_s$
MEASUREMENT	ELH	A'	B'	FULL STANDARD	$I_s$

Calibration and Measurement Procedures for Amorphous Cells

	RADIATION TYPE	SOURCE INTENSITY	SOURCE SPECTRAL DIST.	CELL	I(out)
SPECTRAL CALIBRATION	ELH	A	B	MFG SAMPLE	$I(1)...I(n)$
	ELH	A	B	SI DIODE REF	$I(1)...I(n)$
INTENSITY CALIBRATION	NATURAL	1-SUN	1-SUN	MFG SAMPLE	$I_0$
	ELH	A'	B'	MFG SAMPLE	$I_0$
	ELH	A'	B'	SI DIODE REF	$I_s$
MEASUREMENT	ELH	A''	B''	SI DIODE REF	$I_s$

## MODULE DEVELOPMENT AND ENGINEERING SCIENCES

IN GENERAL,

$$j = \int_{\text{spectrum}} I(\lambda) \cdot R(\lambda) d\lambda$$

where  $j$  = short circuit current density ( $A/cm^2$ )  
 $I(\lambda)$  = illumination intensity ( $W/cm^2 / \mu m$ )  
 $R(\lambda)$  = solar cell response ( $A/W$ )

FOR AN a-Si CELL

$$j(a) = I(\lambda_1) R_a(\lambda_1) \Delta\lambda + I(\lambda_2) R_a(\lambda_2) \Delta\lambda + \dots + I(\lambda_n) R_a(\lambda_n) \Delta\lambda$$

FOR A c-Si CELL

$$j(c) = I(\lambda_1) R_c(\lambda_1) \Delta\lambda + I(\lambda_2) R_c(\lambda_2) \Delta\lambda + \dots + I(\lambda_n) R_c(\lambda_n) \Delta\lambda$$

THE PROGRAMMABLE REFERENCE CELL CONSISTS OF  $n$  BAND PASS ( $\Delta\lambda$ ) FILTERED DIODES, EACH HAVING A SEPARATE AMPLIFIER (GAIN =  $A$ ). THE SHORT CIRCUIT CURRENT FROM EACH DIODE IS ADDED TO GIVE A TOTAL CURRENT VALUE OF:

$$i(P) = A_1 I(\lambda_1) R_c(\lambda_1) \Delta\lambda + A I(\lambda_2) R_c(\lambda_2) \Delta\lambda + \dots + A_n I(\lambda_n) R_c(\lambda_n) \Delta\lambda$$

IF THE AMPLIFIER GAINS ARE ADJUSTED IN THE COMPUTER SUCH THAT

$$A_n = C \cdot R_a(\lambda_n) / R_c(\lambda_n)$$

WHERE  $C$  IS A CONSTANT SUCH THAT  $i(P)$  = CURRENT UNDER 1-SUN ILLUMINATION. THEN

$$i(P) = C \cdot j(a)$$

AND THE FILTERED DIODE ARRAY WILL ACT AS A SIMULATED REFERENCE CELL.

CALIBRATION REQUIRES DETERMINING:

- 1) SPECTRAL RESPONSE RATIOS OF FILTERED SILICON DIODES AND UNKNOWN CELL
- 2) VALUE OF CONSTANT,  $C$ .

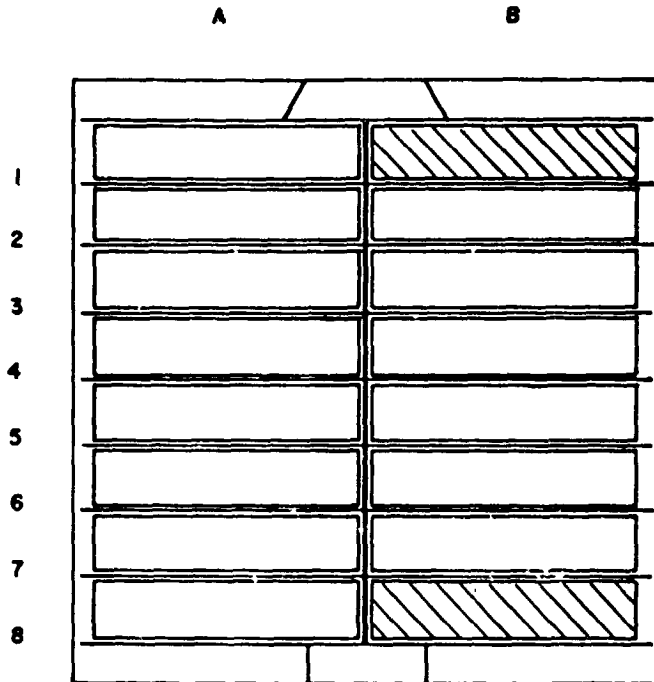
ACCURACY OF CALIBRATION WILL DEPEND ON THE NUMBER OF DIODES USED AND THE WIDTH OF THE BAND PASS FILTERS.

BECAUSE OF ITS SMALL AREA, THE SIMULATED REFERENCE CELL DOES NOT PERFORM SPATIAL AVERAGING. HENCE UNIFORM ILLUMINATION IS REQUIRED.

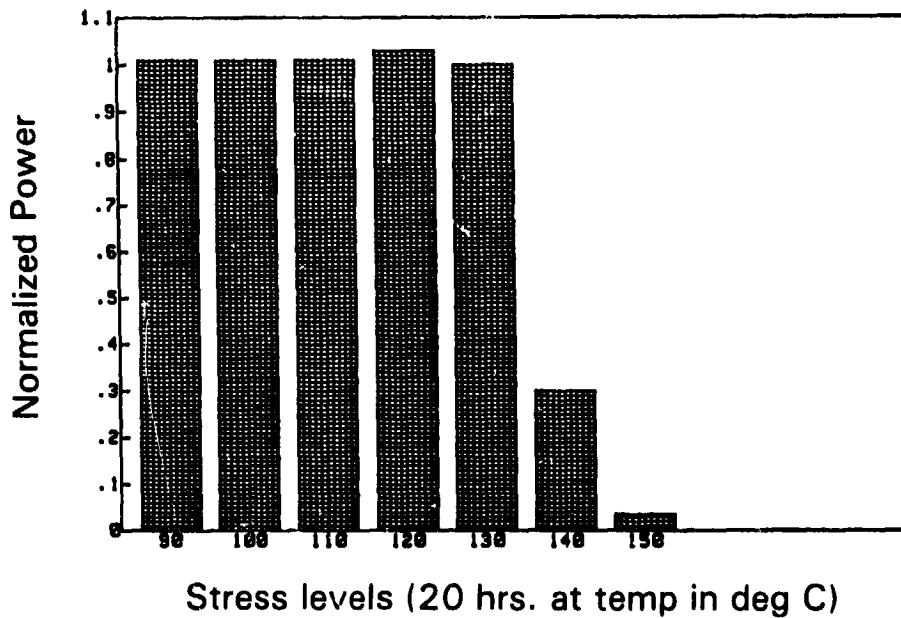


MODULE DEVELOPMENT AND ENGINEERING SCIENCES

Diagram of Step Stress Submodule Showing Location of Two "Bad" Cells



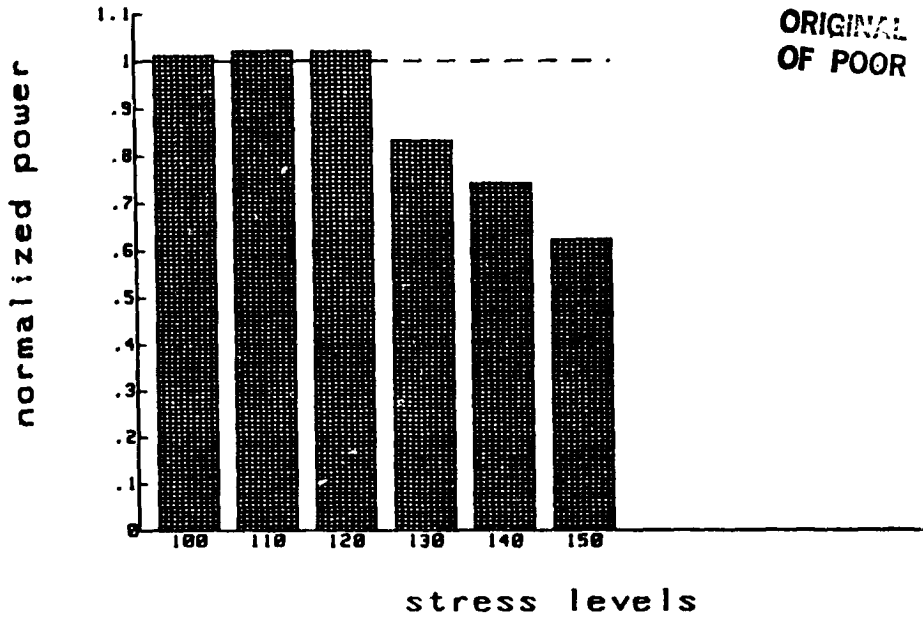
Temperature Step Stress



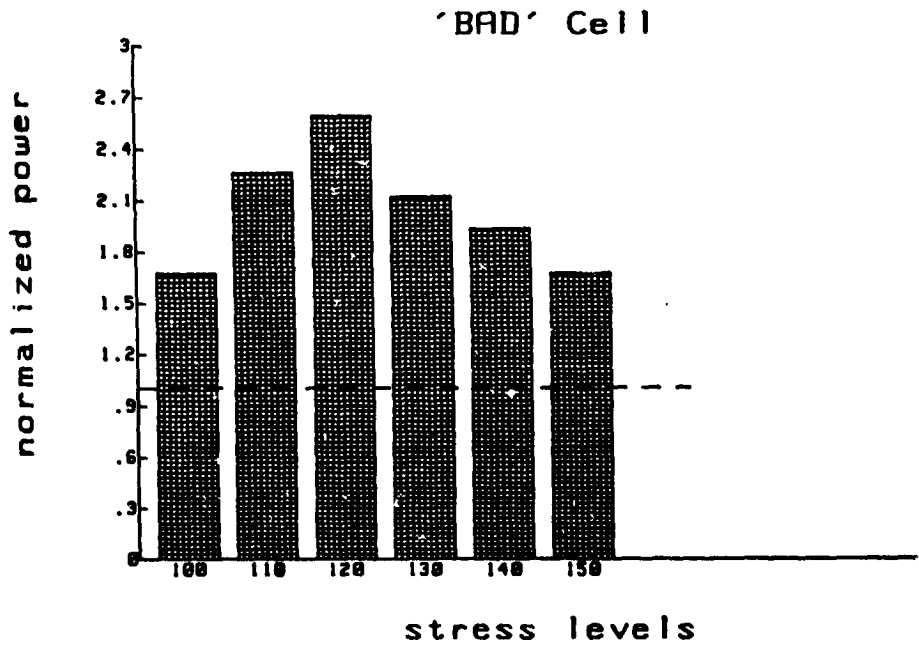


MODULE DEVELOPMENT AND ENGINEERING SCIENCES

Temperature Step Stress: "Good" Cell  
(20 h at Temperature in Degree C)



Temperature Step Stress: "Bad" Cell  
(20 h at Temperature in Degree C)



Temperature Step Stress

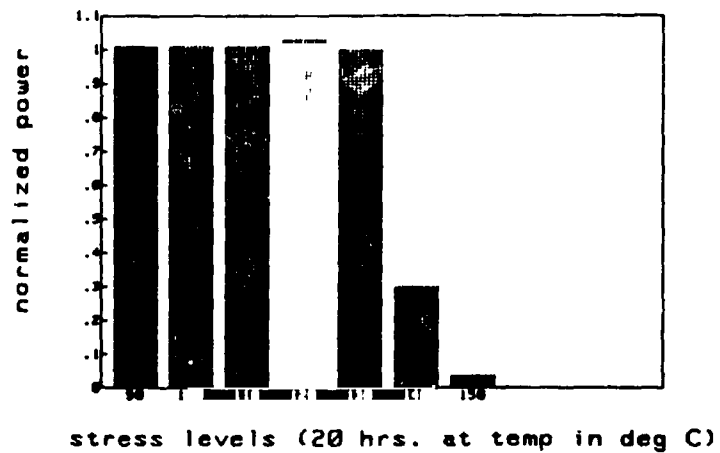


Figure 1. Average Normalized Power Output as a Function of Stress Level Temperature for 16 Amorphous Silicon Solar Cells.

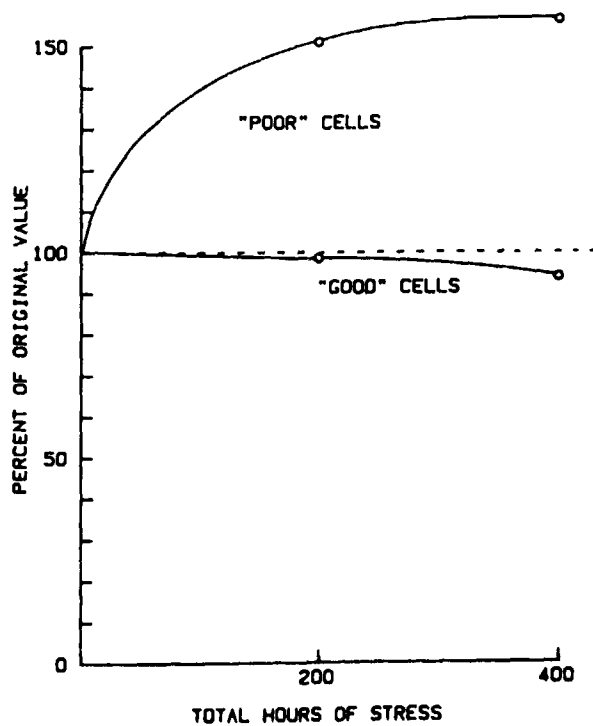


Figure 2. Average Normalized Power Output of Amorphous Silicon Solar Cells as a Function of 85/85 Stress Time.